

MIF had the privilege of welcoming Prof. Shuichi Shoji of Waseda University's Faculty of Science and Engineering and Associate Prof. Yoshio Mita of the University of Tokyo's Graduate School of Engineering.

Prof. Shoji introduced a case study entitled "MEMS devices designed for cell function analysis" on applied MEMS devices that enable a cell culture system, cell disruption, and biomolecular separation and analysis for analyzing the functions of specific cells. Associate Prof. Mita introduced an innovative MEMS technology in his lecture entitled "Study on MEMS integrated through an autonomous distributed micro-robot." As an example, he described a MEMS device that moves autonomously over a water surface according to low-voltage



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electrowetting-on-dielectrics (EWOD) droplet propulsion employing a three-dimensional photodiode structure having a depth of 10 μ m and a width of 150 nm.

Dissemination and Publicity Projects

The Micromachine Center (MMC) publishes newsletters, holds exhibitions, and distributes information on its Web site as a means of disseminating information on micromachines and MEMS to educate the general public and of making information on its activities widely available. This article will describe some of the MMC's recent activities.

1. Expansion of Participants in the MEMS Mall

The MEMS Mall was launched on October 1, 2008 on the MMC Web site to provide information on products and technologies developed by MEMS-related companies. While participation in the mall was limited last year to members of the MEMS Industry Forum (MIF), this year we have relaxed the requirements to include non-member companies.

In the past, a person wishing to collect information on MEMS products had to access each company's Web site individually. The MEMS Mall is a site that brings all MEMS product information together and provides online visitors a method of accessing information, much like visiting booths at the MMC-sponsored Exhibition Micromachine/MEMS. To participate in the MEMS Mall, please visit the following Web site.

<http://www.mmc.or.jp/mall/>

2. MemsONE Sales and Distribution

Sales and distribution of the MEMS design and analysis software MemsONE began in February this year. The software was developed under the project entitled the MEMS Open Network Engineering System of Design Tools and has been receiving glowing reviews. An academic version of the software for universities and public research institutions is distributed by the MMC, while an enterprise version designed for general company use is sold through software vendors.

See the table below for the schedule of MemsONE training courses to be held in Tokyo and Osaka. For more information on the training courses and features of the MemsONE software, please visit the following Web site.

<http://mmc.la.coocan.jp/mems-one/>

Schedule of training courses

Tokyo	Osaka
5/19 (Tue) : Basic operations	5/22 (Fri) : Basic operations
6/22 (Mon) : Analysis	7/17 (Fri) : Analysis
9/18 (Fri) : Applications	
10/21 (Wed) : Basic operations	
11/18 (Wed) : Analysis	
1/20 (Wed) : Applications	

3. Micro/Nano 2009

The general exhibition Micro/Nano 2009 provides a venue for businesses in the micromachine and MEMS industries to showcase their leading-edge products and materials and to

present their latest research findings. Details of the event are given below.

(1) 20th Exhibition Micromachine/MEMS

The world's largest exhibition covering both the micromachine and MEMS industries, the 20th Exhibition Micromachine/MEMS will be held July 29–31, 2009. At Tokyo Big Sight (Tokyo International Exhibition Center), East Hall. Some special exhibits are planned for the event to commemorate its 20th anniversary.

(2) Seminars and symposiums

This year, two special conference areas A and B will be set up at the venue of Exhibition Micromachine/MEMS for holding various presentations on micro/nano-related research activities. The following table shows the schedule of events for these conference areas.

	Conference area A	Conference area B
7/29 (Wed)	10:25–16:45 The International Micromachine/Nanotech Symposium – MEMS World –	11:00–12:20 MEMS Industry Forum Workshop on Industry-Academia Collaboration 13:00–15:50 MEMS Packaging Forum
7/30 (Thu)	Japanese-German Micro/Nano Business Forum	11:00–12:20 MEMS Industry Forum Workshop on Industry-Academia Collaboration 13:15–17:00 BEANS Project Seminar
7/31 (Fri)	10:30–16:15 MIF Forum	10:30–16:45 Presentation of Results from the Fine MEMS Project

For more information on the exhibition and visitor registration, visit the Web site (<http://www.micromachine.jp>).

The 19th Exhibition Micromachine/MEMS held in 2008

